

Substitute for form 1449A/PTO				<i>Complete if Known</i>	
INFORMATION DISCLOSURE STATEMENT BY APPLICANT <i>(use as many sheets as necessary)</i>				Application Number	Not Yet Assigned 10/719177
Sheet	1	of	3	Filing Date	Herewith
				First Named Inventor	Miller, David
				Art Unit	Not Yet Assigned 2834
				Examiner Name	Not Yet Assigned T. Dougherty
				Attorney Docket Number	019930-002840

U.S. PATENT DOCUMENTS*					
Examiner Initials*	Cite No. ¹	Document Number	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number Kind Code ² (if known)			
MB	AA	5,414,540	05/09/95	Patel et al.	
MB	AB	5,917,625	06/29/99	Ogusu et al.	
MB	AC	5,999,672	12/07/99	Hunter et al.	
MB	AD	6,028,689	02/22/00	Michalicek et al.	
MB	AE	6,040,935	03/21/00	Michalicek	
MB	AF	6,097,859	08/01/00	Solgaard	
MB	AG	6,108,471	08/22/00	Zhang et al.	
MB	AH	6,128,122	10/03/00	Drake et al.	
MB	AI	09/442,061	11/16/99	Weverka, et al.	
	AJ	US-			
	AK	US-			
	AL	US-			
	AM	US-			
	AN	US-			
	AO	US-			
	AP	US-			
	AQ	US-			
	AR	US-			
	AS	US-			
	AT	US-			

FOREIGN PATENT DOCUMENTS							
Examiner Initials*	Cite No. ¹	Foreign Patent Document		Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	T ⁶
		Country Code ³	Number ⁴				
	AU						<input type="checkbox"/>
	AV						<input type="checkbox"/>
	AW						<input type="checkbox"/>
	AX						<input type="checkbox"/>
	AY						<input type="checkbox"/>
	AZ						<input type="checkbox"/>
	BA						<input type="checkbox"/>
	BB						<input type="checkbox"/>

Examiner Signature	<i>Thomas M. Dougherty</i>	Date Considered	3-2-05
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Sheet <u>2</u>		of <u>3</u>	Attorney Docket Number <u>019930-002840</u>		

NON PATENT LITERATURE DOCUMENTS					
Examiner Initials *	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.			T ²
<u>TMD</u>	BC	T. Akiyama, et al.; "Controlled Stepwise Motion in Polysilicon Microstructures," <i>Journal of Microelectromechanical Systems</i> , Vol. 2, No. 3, September 1993; pp.106-110			
<u>TMD</u>	BD	Kenneth Bean, et al., "Anisotropic Etching of Silicon," <i>IEEE Transactions on Electron Devices</i> , Vol. Ed-25, No. 10, October 1978			
<u>TMD</u>	BE	Dino R. Ciarlo, "A latching accelerometer fabricated by the anisotropic etching of (110) oriented silicon wafers," <i>Lawrence Livermore Nat'l Laboratory</i> , March 1, 1992			
<u>TMD</u>	BF	A.S. Dowa, et al., "Development of a Silicon Two-Axis Micromirror for an Optical Cross-Connect," <i>Solid State Sensors and Actuators Workshop</i> , Hilton Head, South Carolina, pp. 93-96			
<u>TMD</u>	BG	Joseph Ford et al., "Wavelength Add Drop Switching Using Tilting Micromirrors," <i>Journal of Lightwave Technology</i> , Vol. 17, No. 5, May 1999			
<u>TMD</u>	BH	J. Grade et al., "A Large-Deflection Electrostatic Actuator for Optical Switching Applications, <i>Solid-State Sensor and Actuator Workshop</i> , Hilton Head Island, South Carolina, June 4-8, 2000; pp. 97-100			
<u>TMD</u>	BI	V. Kaajakari et al.; "Ultrasonic Actuation for MEMS Dormancy-Related Stiction Reduction," <i>In MEMS Reliability for Critical Applications, Proceedings of SAPIE Vol. 4180 (2000)</i> ; pp. 60-65			
<u>TMD</u>	BJ	T.L. Koch et al., "Anisotropically etched deep gratings for InP/InGaAsP optical devices," <i>J.App. Phys.</i> 62 (8), 15 October 1987			
<u>TMD</u>	BK	I. Nishi et al., "Broad-Passband-Width Optical Filter for Multi-Demultiplexer Using a Diffraction Grating and a Retroreflector Prism," <i>Electronics Letters</i> , Vol. 21, No. 10, 9 th May 1985			
<u>TMD</u>	BL	P. Phillippe et al., "Wavelength demultiplexer: using echelle gratings on silicon substrate," <i>Applied Optics</i> , Vol. 24, No. 7, 1 April 1985			
<u>TMD</u>	BM	M. Schilling et al., "Deformation-free overgrowth of reactive ion beam etched submicron structures in InP by liquid phase epitaxy," <i>Appl. Phys. Lett.</i> 49 (12), 22 September 1986			
<u>TMD</u>	BN	Z. J. Sun et al., "Demultiplexer with 120 channels and 0.29-nm Channel Spacing," <i>IEEE Photonics Technology Letters</i> , Vol. 10, No. 1, January 1998			
<u>TMD</u>	BO	W. Tang, et al., "Electrostatically Balanced Comb Drive for Controlled Levitation," <i>Reprinted from Technical Digest IEEE Solid-State Sensor and Actuator Workshop</i> , June 1990; pp. 198-202			
<u>TMD</u>	BP	L. Torcheux et al., "Electrochemical Coupling Effects on the Corrosion of Silicon Samples in HF Solutions," <i>J. Electrochem.Soc.</i> , Vol. 142, No. 6, June 1995			

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<i>TMD</i>		P. VanKessel et al., "A MEMS-Based Projection Display," Proceedings of the IEEE, Vol. 86, No. 8, August 1998; pp. 1687-1704	
<i>TMD</i>		Microfabricated Silicon High Aspect Ratio Flexures for In-Plane Motion; dissertation by C. Keller, Fall 1998	
<i>TMD</i>		Gimballed Electrostatic Microactuators with Embedded Interconnects; dissertation by L. Muller; Spring 2000	

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